

Serial No.: 09/846,795

Filing Date: May 1, 2001

Attorney Docket No. 125.013US02

Title: BONDED SUBSTRATE FOR AN INTEGRATED CIRCUIT CONTAINING A PLANAR INTRINSIC GETTERING ZONE

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monocrystalline semiconductor material below said selected depth comprising a second layer of the undamaged monocrystalline semiconductor material;

heating said wafer under conditions effective to convert said amorphous semiconductor layer to a first layer of the monocrystalline semiconductor material;

heating the wafer under conditions effective to coalesce said zone of monocrystalline semiconductor material damaged by lattice defects, thereby forming a substantially planar intrinsic gettering zone comprising substantially pure semiconductor material and including active gettering sites, said gettering zone being disposed substantially at said selected depth;

providing a handle wafer comprising on one surface an insulating bond layer; and

bonding said insulating bond layer to said surface of said wafer, thereby forming a bonded semiconductor-on-insulator substrate comprising a handle wafer, an insulating bond layer, and a monocrystalline semiconductor device wafer, said device wafer containing a substantially planar intrinsic gettering zone that comprises substantially pure semiconductor material and includes active gettering sites;

forming a semiconductor device on said second layer of undamaged monocrystalline semiconductor material or on layer of epitaxial monocrystalline semiconductor material deposited on said second layer; and

wherein the said semiconductor device is formed on said epitaxial layer.

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26. (Amended Twice) A semiconductor device formed by the process comprising:

providing a wafer comprising a monocrystalline semiconductor material;

implanting ions of the semiconductor material through a surface of the monocrystalline semiconductor wafer to a selected depth in said wafer, thereby forming adjacent to said surface an amorphous layer of the semiconductor material, said amorphous semiconductor layer extending to a substantially planar zone disposed at substantially said selected depth and comprising monocrystalline semiconductor material damaged by lattice defects, undamaged monocrystalline semiconductor material below said selected depth comprising a second layer of the undamaged monocrystalline semiconductor material;

heating said wafer under conditions effective to convert said amorphous semiconductor layer to a first layer of the monocrystalline semiconductor material;

heating the wafer under conditions effective to coalesce said zone of monocrystalline semiconductor material damaged by lattice defects, thereby forming a substantially planar intrinsic gettering zone comprising substantially pure semiconductor material and including active gettering sites, said gettering zone being disposed substantially at said selected depth between the first layer of monocrystalline semiconductor material and the second layer of undamaged monocrystalline semiconductor material;

providing a handle wafer comprising on one surface an insulating bond layer; and

bonding said insulating bond layer to said surface of said wafer adjacent the first layer of monocrystalline semiconductor material, thereby forming a bonded semiconductor-on-insulator substrate comprising a handle wafer, an insulating bond layer, and a monocrystalline semiconductor device wafer, said device wafer containing a substantially planar intrinsic gettering zone that comprises substantially pure semiconductor material and includes active gettering sites;

wherein said monocrystalline semiconductor material comprises silicon and said implanted ions comprise silicon ions;

wherein said handle wafer comprises silicon and said insulating bond layer comprises silicon dioxide; and

forming a semiconductor device on said bonded substrate.

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28. (Amended Once) A bonded semiconductor-on-insulator substrate for semiconductor devices and integrated circuits, said substrate comprising:

a wafer comprising a monocrystalline semiconductor material and having a first surface and a second surface, said wafer comprising a first layer of the monocrystalline semiconductor material adjacent to said first surface and a second layer of undamaged monocrystalline semiconductor material adjacent to said second surface, and interposed between said first and second layers of the monocrystalline semiconductor material, a substantially planar intrinsic

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gettering zone comprising substantially pure semiconductor material and including active gettering sites,

an insulating bond layer disposed on said first surface of said wafer;

and

a handle wafer bonded to said insulting bond layer.

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30. (Amended Twice) The substrate of claim 28 wherein the monocrystalline semiconductor material comprises silicon and the substantially planar intrinsic gettering zone is formed by implanting ions of silicon through the first layer of monocrystalline semiconductor material.

38. (Amended Once) A bonded semiconductor-on-insulator substrate for an integrated circuit comprising:

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a wafer, the wafer having a first layer of monocrystalline semiconductor material adjacent a first surface of the wafer, the wafer further having a second layer of undamaged monocrystalline semiconductor material adjacent a second surface of the wafer, the wafer further having a substantially planar intrinsic gettering zone of substantially pure semiconductor material and active gettering sites positioned between the first and second layers formed by implanting ions of the semiconductor material through the first layer of monocrystalline semiconductor material;

a handle wafer; and

an insulating bond layer bonding the handle wafer to the first surface of the wafer.

39. (Amended Once) The bonded semiconductor-on-insulator substrate for an integrated circuit of claim 38, wherein the first and second layers of monocrystalline semiconductor comprises silicon and the ions implanted through the first layer are silicon ions.

40. (Amended Once) The bonded semiconductor-on-insulator substrate for an integrated circuit of claim 38, wherein the second layer of undamaged monocrystalline semiconductor material is a device layer upon which semiconductor devices are formed.

AMENDMENT AND RESPONSE

PAGE 5

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[ 45. Canceled ]

CM 46. (Amended Once) The bonded semiconductor-on-insulator substrate for an integrated circuit of claim 38, further comprising:

a layer of epitaxial monocrystalline semiconductor material deposited on the second layer.

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